Attorney Docket No. Application No.: INFORMATION DISCLOSURE CITATION 10/807,376 024445-451 (Use several sheets if necessary) Applicant(s): Björn LJUNGBERG Page 1 of 1 Filing Date: Group Art Unit: 1775 March 24, 2004 U.S. PATENT DOCUMENTS \*Examiner **Document** Sub Initial Number Name Class Class Filing Date Date **FOREIGN PATENT DOCUMENTS Document** Sub Translation Number Date Country Class Class YES NO OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.) Ch. Täschner et al., "Deposition of hard crystalline Al<sub>2</sub>O<sub>3</sub> coatings by pulsed d.c. PACVD", Surface and Coatings Technology 116-119, 1999 Elsevier Science S.A., pp. 891-897. O. Zywitzki et al., "Correlation between structure and properties of reactively deposited Al<sub>2</sub>O<sub>3</sub> coatings by pulsed magnetron sputtering", Surface and Coatings Technology 94-95, 1997 Elsevier Science S.A., pp. 303-308.

Date Considered

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